

ABSTRACT

WAFER TRANSFER SUPERVISION CONTROL METHOD AND SYSTEM, COMPUTER DEVICE, AND STORAGE MEDIUM

Disclosed are a wafer transfer supervision control method and system, a computer device, and a storage medium, relating to the field of wafer transfer control. The method includes: generating, by a manufacturing execution unit, a transfer instruction, where the transfer instruction includes a plurality of commands, and the plurality of commands are jointly indicative of a first transfer path based on an instruction sequence of the first transfer path (201); receiving, by a material control unit, the transfer instruction sent according to the instruction sequence of the first transfer path (202); obtaining, by the material control unit, transfer state information of the target wafer indicated in the transfer instruction (203); adjusting, by the material control unit, the first transfer path indicated in the transfer information according to the transfer state information, generating a target transfer path of the target wafer, and sending the target transfer path to a material handling unit according to an instruction sequence of the target transfer path (204); and controlling the material handling unit to transport the target wafer according to the target transfer path sent by the material control unit (205). A plurality of commands can be transmitted at a time, and interaction time and frequency of transmission between different units are reduced, thus increasing a program processing speed.

FIG. 2